

Design rules-1

Modern VLSI Design 4e: Chapter 2

Copyright © 2008 Prentice Hall PTR

Why we need design rules

Design rules for a process are formulated to minimize the occurrence of common fabrication problems and bring the yield of correct chips to an acceptable level

- Better area efficiency
- Better yield
- Better reliability
- Increase the probability of fabricating a successful product on Si wafer

Modern VLSI Design 4e: Chapter 2

Copyright © 2008 Prentice Hall PTR

What's happened?



Modern VLSI Design 4e: Chapter 2

Copyright © 2008 Prentice Hall PTR

Design rules and yield

- Design rules are determined by manufacturing process characteristics.
- Design rules should provide adequate yield if followed.
- Types of design rules:
 - Industry Standard: Micron Rule
 - λ Based Design Rules
- *Spacing, Separation, Composition.*

Modern VLSI Design 4e: Chapter 2

Copyright © 2008 Prentice Hall PTR

Design rules and yield...

- Minimum length or width of a feature on a layer is 2λ
 - To allow for shape contraction
- Minimum separation of features on a layer is 2λ
 - To ensure adequate continuity of the intervening materials.

Modern VLSI Design 4e: Chapter 2

Copyright © 2008 Prentice Hall PTR

Manufacturing problems

- Photoresist shrinkage, tearing.
- Variations in material deposition.
- Variations in temperature.
- Variations in oxide thickness.
- Impurities.
- Variations between lots.
- Variations across a wafer.

- Transistor problems
- Wiring problems
- Oxide problems
- Via problems

Modern VLSI Design 4e: Chapter 2

Copyright © 2008 Prentice Hall PTR

Transistor problems

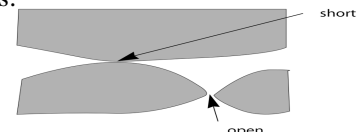
- Variations in threshold voltage:
 - oxide thickness;
 - ion implantation;
 - poly variations.
- Changes in source/drain diffusion overlap.
- Variations in substrate.

Modern VLSI Design 4e: Chapter 2

Copyright © 2008 Prentice Hall PTR

Wiring problems

- Diffusion: changes in doping -> variations in resistance, capacitance.
- Poly, metal: variations in height, width -> variations in resistance, capacitance.
- Shorts and opens:



Modern VLSI Design 4e: Chapter 2

Copyright © 2008 Prentice Hall PTR

Oxide problems

- Variations in height.
- Lack of planarity -> step coverage.



Via problems

- Via may not be cut all the way through.
- Undersize via has too much resistance.
- Via may be too large and create short.



Design rules

- Industry Standard: Micron Rule
 - All device dimensions are expressed in terms of absolute dimension ($\mu\text{m}/\text{nm}$)
 - These rules will not support proportional scaling
- λ Based Design Rules (Developed by Mead & Conway)
 - All device dimensions are expressed in terms of a scalable parameter λ .
 - $\lambda = L/2$; L = The minimum feature size of transistor
 - these rules support proportional scaling.

Scaling theory

- In digital circuit design scaling is possible because the capacitive loads that must be driven by logic gates shrink faster than the currents supplied by the transistors.
- Classical scaling theory runs into complications at nanometer features.
 - Leakage.
 - Smaller supply voltage.

Scaling model

Assume that all the basic physical parameters of the chip are shrunk by a factor $1/x$:

- $\lambda \rightarrow \lambda/x$.
- $W \rightarrow W/x, L \rightarrow L/x$.
- $t_{ox} \rightarrow t_{ox}/x$.
- $N_d \rightarrow N_d/x$.
- $V_{DD} - V_{SS} \rightarrow (V_{DD} - V_{SS})/x$.

Current and capacitance scaling

$$\begin{aligned} \hat{k}'/k' &= x & \hat{V}_t &= V_t/x & \frac{\hat{I}_d}{I_d} &= \left(\frac{\hat{k}'}{k'}\right)\left(\frac{\hat{W}/\hat{L}}{W/L}\right)\left[\frac{(\hat{V}_{gs}-\hat{V}_t)^2}{(V_{gs}-V_t)^2}\right] \\ & & & & &= x\left(\frac{1/x}{1/x}\right)\left(\frac{1}{x}\right)^2 = \frac{1}{x} \end{aligned}$$

- Saturation drain current scales as $1/x$.
- Capacitance scales as $1/x$.
- Total performance over scaling:
 - $[C'V'/I']/[CV/I] = 1/x$

So, as the layout is scaled from λ to $\hat{\lambda} = \lambda/x$, the circuit is actually speeded up by a factor “x”

Interconnect scaling

- Two varieties of interconnect scaling:
 - **Ideal scaling** reduces vertical and horizontal dimensions equally: *the resistance increases with scaling.*
 - **Constant dimension** does not change wiring sizes: *resistance remains same.*
 - Higher levels of interconnect are constant dimension---same as older technologies.

Quiz

Predict how metal 1 and metal 2 resistance would change for a 90 nm process using:

- a) Ideal scaling.
- b) Constant dimension scaling